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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Chen et al. *AS*

Serial No.: 10/661,089

Filed: September 10, 2003

For: METHOD FOR MITIGATING  
CHEMICAL VAPOR DEPOSITION  
PHOSPHORUS DOPING OXIDE  
SURFACE INDUCED DEFECTS

Examiner: Hoang, Quoc Dinh

Group Art Unit: 2818

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**AMENDMENT**

Dear Sir:

In response to the Office Action mailed April 3, 2006, Applicants respectfully request that the following amendments be entered in the above-identified patent application:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 5 of this paper.